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PATENT  
ATTY. DOCKET NO. SAMD/18US3

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Strauss et al.  
Serial No. : 08/881,948  
Filed : June 25, 1997  
For : MECHANICALLY JOINED SPUTTERING TARGET AND ADAPTOR  
THEREFOR

Art Unit: 1109  
Examiner: R. McDonaugh

RECEIVED

MAR 5 1998

Assistant Commissioner of Patents  
Washington, DC 20231

GROUP 1100

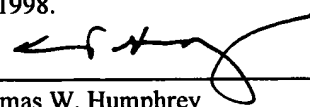
RESPONSE TO OFFICE ACTION

In response to the Office Action mailed December 19,  
1997, please amend the application as follows:

In the Claims:

*SubC'* 9. (Amended) A target for installation in a vacuum  
chamber for processing a substrate by causing sputtering material  
to be ejected from the target onto said substrate, comprising  
a generally disk-shaped section having two generally  
planar surfaces and [a cylindrical] an outer periphery,  
[manufactured homogeneously of said sputtering material,] said  
generally disk-shaped section having at least one radially-inward  
step proximate said outer periphery  
said target being manufactured homogeneously of said  
sputtering material.

I hereby certify that this correspondence is being deposited  
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19, 1998.

  
Thomas W. Humphrey  
Reg. No. 34,353